

MPGD & Active媒質TPC2020研究会

Saturday, 26 December 2020

Session 6 (14:45 - 15:40)

-Conveners: Atsuhiko OCHI

time [id]	title	presenter
14:45[19]	表面抵抗率の異なるDLCを用いたresistive μ -picの基本性能の評価	谷口 大悟
15:10[20]	A novel technique for the measurement of the avalanche fluctuation of a GEM stack using a gating foil	弓野 圭太
15:35[21]	Closing remarks	MIUCHI, Kentaro